

N-515K Non-Magnetic Piezo Hexapod

6-Axis Precision Positioning System with NEXLINE® Linear Drives



6-axis parallel kinematics (Hexapod) with integrated N-215 NEXLINE® high-load actuators, suitable for applications in strong magnetic fields

- Travel Ranges 10 mm Linear, 6° Rotation
- Large Clear Aperture Ø 202 mm
- Non-Magnetic
- Nanometer Resolution
- Low-Profile: 140 mm Height Only
- Parallel Kinematics for Enhanced Dynamics and Better Multi-Axis Accuracy
- Up to 500 N Force Generation
- Self Locking at Rest, No Heat Generation

Model	Travel range	Load capacity	Dimensions
N-515KNPH	X, Y, Z: 10 mm	50 kg	Outer Ø baseplate, 380 mm
NEXLINE®	$\theta_x, \theta_y, \theta_z: 6^\circ$		Ø moved platform (top) 300 mm
Piezo Hexapod			140 mm height

N-510 High-Force NEXLINE® Z/Tip/Tilt Platform

Nanometer Precision for Semiconductor Industry, Wafer Alignment



Z, tip, tilt nanopositioning platform with 3 integrated drives (tripod design)

- Self Locking at Rest, No Heat Generation
- Vacuum Compatible and Non-Magnetic Designs Feasible
- Parallel Kinematics for Enhanced Dynamics and Better Multi-Axis Accuracy
- NEXLINE® Piezo Walking Drive Free from Wear and Tear
- Load Capacity 200 N
- High Precision with Integrated 5 nm Incremental Sensors + Picometer Resolution Dithering Mode

Model	Travel	Load capacity	Linear velocity	Dimensions
N-510 NEXLINE®	1,3 mm	200 N	0.2 mm/s	Ø 360 mm (14.2")
Z, tip, tilt platform	vertical range 10 mrad tilt angle			Clear aperture 250 mm

N-510K High-Stiffness NEXLINE® Z Stage

High-Precision Positioning, with Capacitive Sensors



The N-510KHFS hybrid-drive nanopositioner offers maximum accuracy for semiconductor inspection applications

- Self Locking at Rest, No Heat Generation
- Hybrid Drive: PiezoWalk® plus PICMA®
- Travel Range: 400 µm Coarse + 40 µm Fine
- 2 µm Closed-Loop Resolution
- Direct Metrology:
 - One Single Control Loop with Capacitive Sensors
- High Push and Holding Force to 25 N
- Piezo Walking Drive w/o Wear and Tear & Outstanding Lifetime due to PICMA® Piezo Actuators

Model	Vertical travel	Velocity	Bidirectional repeatability	Load capacity	Dimensions
N-510KHFS	400 µm coarse 40 µm fine	1 mm/sec	50 nm (full travel)	25 N	Ø 300 mm 68.5 mm height
Hybrid-Focus System					

Linear Actuators & Motors

Nanopositioning/Piezoelectrics

Piezo Flexure Stages / High-Speed Scanning Systems

Linear

Vertical & Tip/Tilt

2- and 3-Axis

6-Axis

Fast Steering Mirrors / Active Optics

Piezo Drivers / Servo Controllers

Single-Channel

Multi-Channel

Modular

Accessories

Piezoelectrics in Positioning

Nanometrology

Micropositioning

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